

PATENT APPLICATION

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of
Koichi TERASHIMA, et al.

Appln. No.: 10/544,783

Confirmation No.: 5339

Filed: August 8, 2005

For: METHOD FOR FORMING NICKEL SILICIDE FILM, METHOD FOR
MANUFACTURING SEMICONDUCTOR DEVICE, AND METHOD FOR ETCHING
NICKEL SILICIDE

Docket No: Q89627

Group Art Unit: 1722

Examiner: Pape A. SENE

PETITION FOR EXTENSION OF TIME UNDER 37 C.F.R. § 1.136

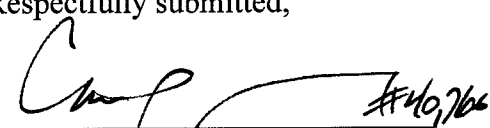
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

Pursuant to 37 C.F.R. § 1.136, Applicant hereby petitions for an extension of time of one month, extending the time for responding to the Office Action of February 12, 2008 to April 12, 2008.

The statutory fee of \$120.00 is being submitted via EFS. The USPTO is directed and authorized to charge all required fees, except for the Issue Fee and the Publication Fee, to Deposit Account No. 19-4880. Please also credit any overpayments to said Deposit Account. A duplicate copy of this sheet is enclosed.

Respectfully submitted,


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Date: April 11, 2008